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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490 : Group Art Unit: 2882

Filed: January 26, 2001 : Examiner: C. Kao

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-

RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON

RADIATION METHOD AND SEMICONDUCTOR DEVICE

PETITION FOR EXTENSION OF TIME

Commissioner for Patents Washington, DC 20231

Sir:

It is respectfully requested that the time for response to the Office Action dated May 23, 2002, now due to expire August 23, 2002, be extended for three months and set to expire on November 23, 2002.

Please charge the extension fee of \$920.00 to Deposit Account No. 500417. Please charge any additional fees or credit any overpayment to Deposit Account No. 500417.

Respectfully submitted,

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Date: November 25, 2002

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